



**PATENT APPLICATION**

**RESPONSE UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER ART UNIT 2823**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of

Koji SUZUKI

Group Art Unit: 2823

Application No.: 09/970,763

Examiner: B. Kebede

Filed: October 5, 2001

Docket No.: 110596

For: **METHOD FOR MONITORING DEPOSITION REACTION DURING PROCESSING  
THE SURFACE OF A SEMICONDUCTOR SUBSTRATE**

**AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the December 17, 2003 Office Action, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**

3/30/2004

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